

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

For: MASK BLANK FOR CHARGED PARTICLE BEAM EXPOSURE, METHOD OF FORMING MASK BLANK AND MASK FOR CHARGED PARTICLE BEAM EXPOSURE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

In response to the office action dated December 14, 2005, for which a three month extension of time is requested to extend the period for response to June 14, 2006, please make the following amendments:

Remarks begin on page 4 of this document.